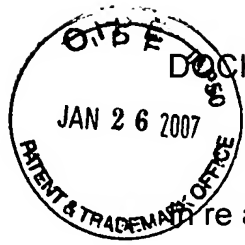


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DOCKET: CU-5415

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

re application of: Wataru SAITO et al.

Serial No.: Division of 10/761,847

Group Art Unit:

Filed: January 21, 2004

Examiner:

For: THIN-FILM TRANSISTOR AND METHOD FOR MANUFACTURING THE SAME

Certification under 37 CFR 1.8(a)

I hereby certify that this paper (along with any paper referred to as being attached or enclosed) is being deposited with The United States Postal Service with sufficient postage as first class mail in an envelope addressed to The Commissioner for Patents, P.O. Box 1450 Alexandria, VA 22313-1450 on January 24, 2007.

Nick Kubacki
Nick Kubacki

The Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

**TRANSMITTAL OF INFORMATION DISCLOSURE STATEMENT (IDS) WITHIN
THREE MONTHS OF FILING OR BEFORE MAILING OF FIRST OFFICE ACTION**

The information disclosure statement submitted herewith is being filed within three months of the filing date of the application or date of entry into the national stage of an international application or before the mailing date of the first Office Action on the merits, whichever event occurs last. 37 CFR 1.97(b).

No fee is believed to be required in view of the above. However, if this is not the case, the Commissioner is authorized to charge our Deposit Account No. 12-0400 for any required fees.

Date: January 24, 2007

[Signature]
W. William Park, Reg. No. 55,523
Ladas & Parry
224 South Michigan Avenue
Chicago Illinois 60604
Tel. No. (312) 427-1300



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Nick Kubacki
Nick Kubacki

The Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT (IDS)

Applicant submits herewith patents, publications or other information of which Applicant is aware, which may be material to the examination of this application and in respect of which there may be a duty to disclose under 37 CFR 1.56.

No paper copies of the U.S. patent references identified in this IDS, if any, are submitted herewith as they are no longer required by the USPTO rules. Only the copies of foreign patent and/or other relevant publication references are submitted herewith.

The filing of this information disclosure statement shall not be construed as a representation that a search has been made (37 CFR 1.97(g)), an admission that the information cited is, or is considered to be, material to patentability or that no other material information exists.

The filing of this information disclosure statement shall not be construed as an admission against interest in any manner. Notice of January 9, 1992, 1135 O.G. 13-25, at 25.

The references submitted herein are listed on PTO-1449 form (modified) enclosed herewith. A copy of each reference listed is being furnished except any duplicate or cumulative patents or publications specified otherwise.


A translation of any foreign language reference, if any, is indicated in PTO-1449 form and being submitted herein if it is readily available. Otherwise it should be construed that such translation is not readily available.

The Statement is made on the basis of the information:

☒ supplied by an individual associated with the filing and prosecution of this application (37 CFR 1.56(c));

Date: January 24, 2007

Respectfully submitted,



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Form PTO-1449 (Modified)

FORM PTO-1449	ATTY. DOCKET NO. CU-5415	SERIAL NO.
INFORMATION DISCLOSURE STATEMENT BY APPLICANT	Applicant Wataru SAITO et al.	
(37 CFR 1.98(b))	FILING DATE January 21, 2005	GROUP

U.S. PATENT DOCUMENTS

EXAMINER INITIAL	PATENT DOCUMENT	ISSUE/PUB DATE	PATENTEE	CLASS	SUB- CLASS	FILING DATE

FOREIGN PATENT OR PUBLISHED FOREIGN PATENT APPLICATION

EXAMINER INITIAL	DOCUMENT NUMBER	PUBL. DATE	COUNTRY OR PATENT OFFICE	CLASS	SUB- CLASS	TRANSLATION YES NO
	JP11-204742	07/30/99	Japan			

OTHER DOCUMENTS (Including Author, Title, Date, Place of publication)

		"Recent Trend of Nanoimprint Technique." Taniguchi et al. Journal of Japan Society of Grinding Engineers. ©2002. vol. 46, issue 6, p. 282-285.
		"Low Temperature Polycrystalline Si Film Formation Technique, A Key To Realize Large-Area Highly Precise TFT Liquid Crystal Displays." Setsuo Usui. Nikkei Business Publications, Inc. ©1991. p. 117-128.
EXAMINER	DATE CONSIDERED	
EXAMINER: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.		

(Form PTO-1449)
1-24-07